

**RESPONSE UNDER 37 C.F.R. § 1.116  
EXPEDITED PROCEDURE**

**IN THE UNITED STATES PATENT AND TRADEMARK OFFICE**

In re the Application of: Confirmation No.: 5377  
Makiko KITAZOE, et al Art Unit: 1792  
Application No.: 10/591,905 Examiner: Keath T. CHEN  
Filed: November 6, 2006 Attorney Docket No.: 029567-00010  
For: SELF-CLEANING CATALYTIC CHEMICAL VAPOR DEPOSITION APPARATUS  
AND CLEANING METHOD THEREOF

**AMENDMENT FILED WITH REQUEST FOR CONTINUED EXAMINATION**

**MAIL STOP RCE**  
Commissioner for Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450

December 18, 2008

Sir:

In reply to the June 19, 2008, Office Action and the November 14, 2008 Advisory Action, the period for reply being extended by the attached Petition for Extension of Time, and upon grant of the attached Request for Continued Examination (RCE), please amend the above-identified application as follows:

Amendments to the claims, as reflected in the listing of claims, being on page 2; and

Remarks begin on page 7.